Amendments to the Claims:

Please cancel Claims 1-36 and 41-52 as indicated in the following listing of claims, which replaces all prior versions and listings of claims in the application.

Listing of Claims:

- 37. (Original) An ion implantation system comprising:
 an ion source having a toroidal plasma generator, and
 an ion source aperture aligned essentially along a center line of the toroidal
 plasma generator.
- 38. (Original) The ion implantation system of claim 37 further comprising a first extraction electrode disposed to accelerate ions from the ion source toward a second extraction electrode.
- 39. (Original) The ion implantation system of claim 37 wherein the toroidal plasma generator includes a first core and a second core, the first core and the second core being aligned essentially along a center line of the toroidal plasma generator.
- 40. (Original) A method of providing ions to an ion implantation system, the method comprising:

providing an ion precursor to a transformer-coupled toroidal plasma generator in an ion source;

ionizing at least a portion of the ion precursor into ions, the ions having a greater density at a center of the transformer-coupled toroidal plasma generator and extending along a line through the center of the transformer-coupled toroidal plasma generator; and ejecting a portion of the ions out of the ion source.

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53. (New) The ion implantation system of claim 37 wherein the ion source is a multicore plasma generator comprising:

an inlet configured to receive a plasma precursor, the inlet in fluid communication with a first plasma current path and with a second plasma current path;

a first conduit passing through a first transformer core; and a second conduit passing through a second transformer core, wherein the first conduit is essentially colinear with the second conduit.

54. (New) The ion implantation system of claim 37 wherein the ion source is a multicore plasma generator comprising:

an outer shell surrounding a first inner shell housing a first toroidal transformer core; and

a second inner shell housing a second toroidal transformer core, wherein the first toroidal transformer core and the second toroidal transformer core are disposed along the center line.

- 55. (New) The ion implantation system of claim 54 wherein the first inner shell is supported within the outer shell by a web allowing circulation of secondary plasma current around the first inner shell within the outer shell.
- 56. (New) The ion implantation system of claim 55 wherein the web contains an electrical lead connected to a primary coil disposed to couple electromagnetic energy to the first toroidal transformer core.
- 57. (New) The ion implantation system of claim 54 wherein the first inner shell includes a shaped bottom portion to provide a circular cross section to the first inner shell.
- 58. (New) The method of claim 40 wherein the ion source is a multicore plasma generator comprising:

an outer shell surrounding a first inner shell housing a first toroidal transformer core; and

a second inner shell housing a second toroidal transformer core, wherein the first toroidal transformer core and the second toroidal transformer core are disposed along the center line.

- 59. (New) The method of claim 58 wherein the first inner shell is supported within the outer shell by a web allowing circulation of secondary plasma current around the first inner shell within the outer shell.
- 60. (New) The method of claim 59 wherein the web contains an electrical lead connected to a primary coil disposed to couple electromagnetic energy to the first toroidal transformer core.
- 61. (New) The method of claim 58 wherein the first inner shell includes a shaped bottom portion to provide a circular cross section to the first inner shell.